# **Oxide nanostructures by ALD and hydrothermal methods for** photovoltaic applications

Rafał Pietruszka, Bartłomiej S. Witkowski, Monika Ożga, Marek Godlewski Institute of Physics Polish Academy of Sciences, Al. Lotnikow 32/46, 02-668 Warsaw, Poland

## **INTRODUCTION**

We developed innovative oxide nanostructures for application potential in the photovoltaic (PV) industry, in particular as three-dimensional transparent electrodes, simplified Si cells and antireflective layers for PV cells of different generations. In addition, a novel technology of CuO absorbing layer, an alternative to CdTe layers, is developed. We use two growth methods of oxides - atomic layer deposition (ALD) method and a novel modification of a hydrothermal method.

## ALD

### ALTERNATIVE SUPPLY OF



## **HYDROTHERMAL METHOD**

No need for sophisticated and expensive equipment

Growth possible on almost any type of substrate

Growth at low temperature (below 100°C)



#### COMPONENTS

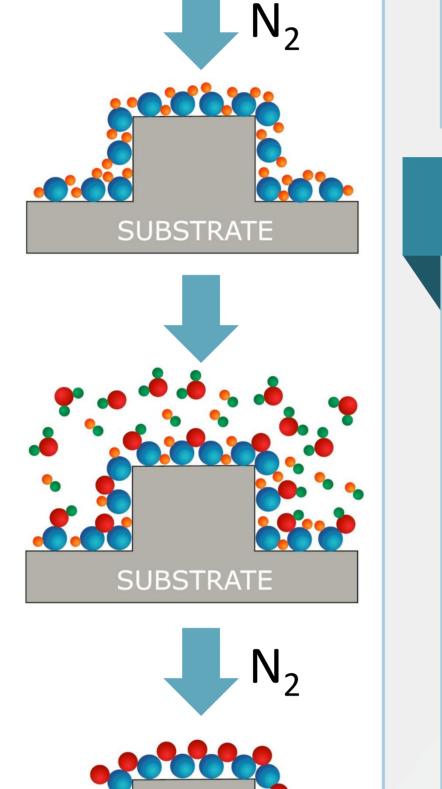
- No reaction in a gas phase
- Possibility of use of reactive precursors
- Low growth temperature is possible

### **HIGH UNIFORMITY**

Uniform covering of very complicated structures

### **SELF-LIMMITING PROCESS**

- Growth rate is NOT  $\bullet$ dependent on flux homogeneity
- Maximal growth rate: 1 monolayer per cycle

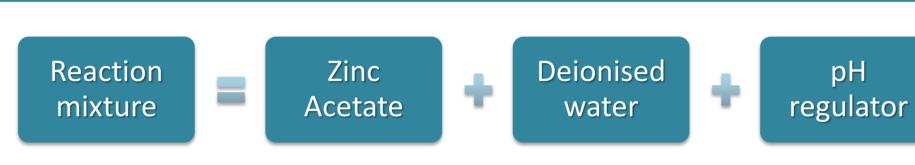


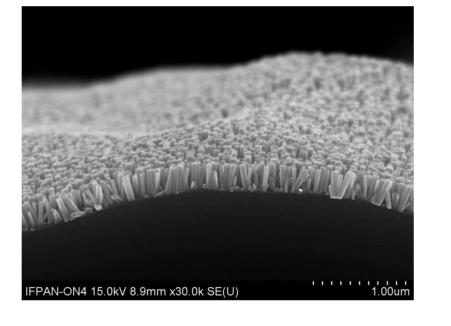
SUBSTRATE

SUBSTRATE

## **GROWTH OF ZnO NRs**

Simple control of nanostructures sizes





Very high growth rate

lacksquare

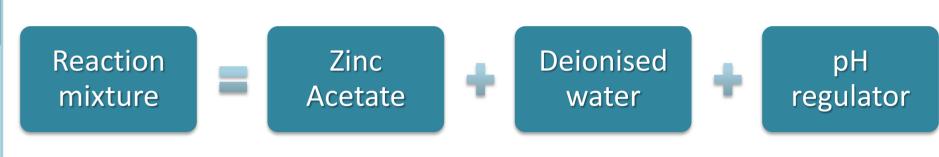
ullet

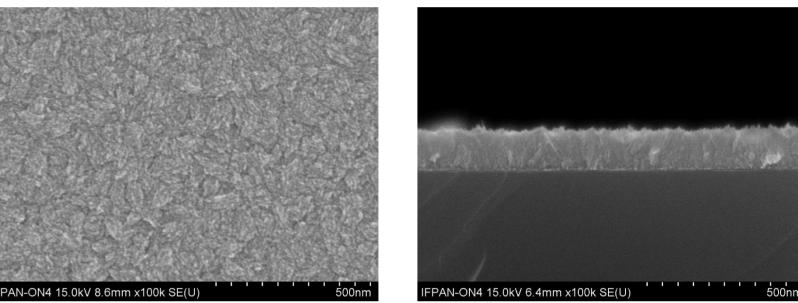
Growth time: 1-2 minutes

Total cost of NRs growth (15.6x15.6 cm<sup>2</sup>): **0.04 EUR** Patent no. PL226487

# Nucleated substrate Temperature

## **GROWTH OF CuO THIN FILMS**

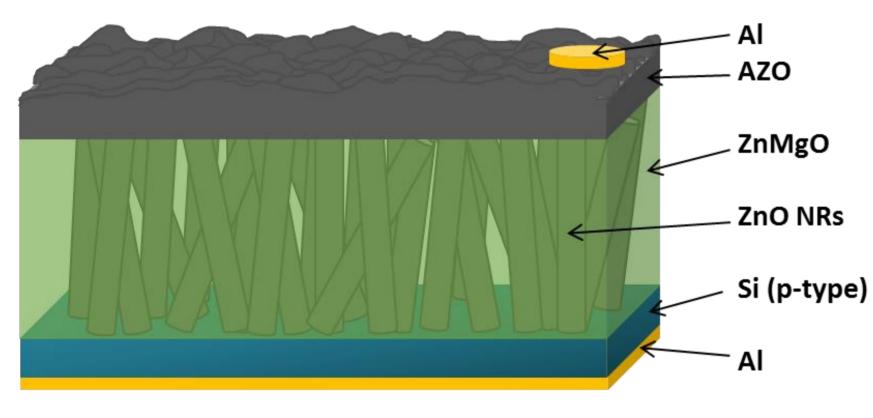




Growth time: 40 s – 6 minutes Total cost of growth (15.6x15.6 cm<sup>2</sup>): **0.06 EUR** Patent application no. P.429066

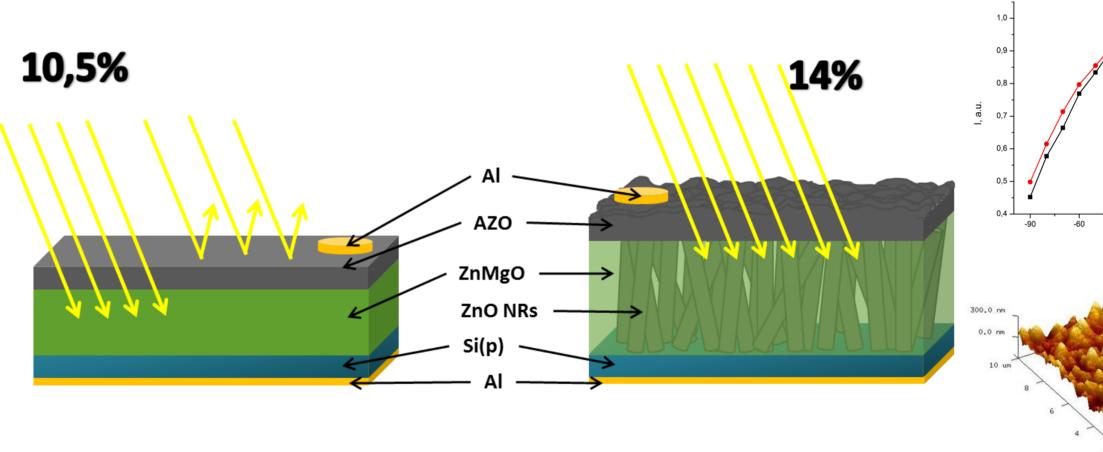
## **3D TRANSPARENT ELECTRODE**

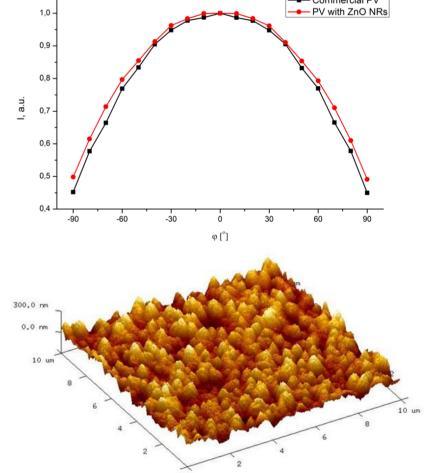
The developed electrode is a combination of ZnO nanorods grown by the hydrothermal method and doped ZnO layers obtained by the ALD method.



**Patent no. PL227817** 

- High transparency
- Expanded surface without the use of toxic processes
- Improved light trapping
- Increasing the efficiency of PV cells
- Cost reduction

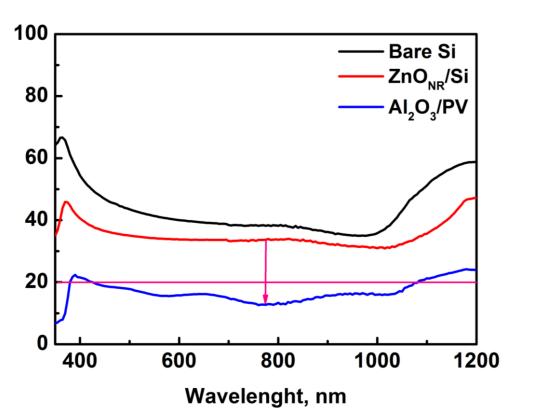




## **ANTIREFLECTIVE LAYERS**

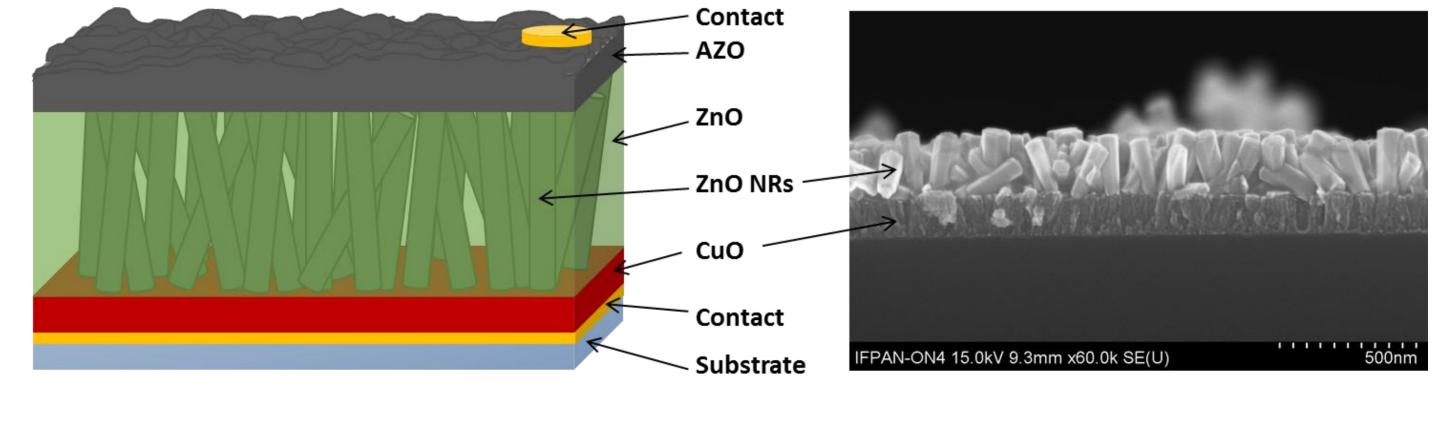
Antireflective layers consist of nano-layers selected in the right order, type and thickness based on their light reflection coefficients.

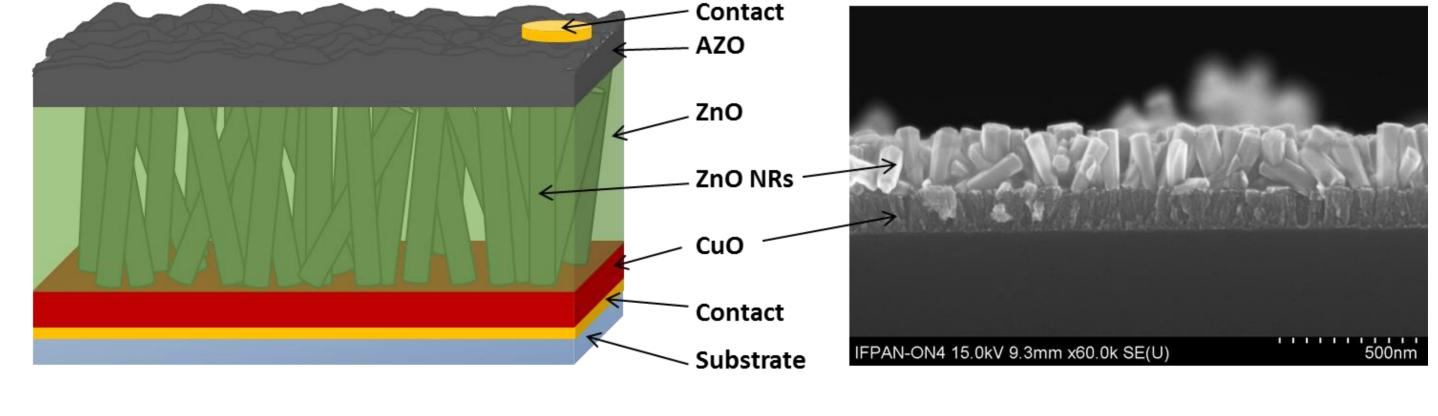
- Reduction of reflected light
- Improving the efficiency of PV cells
- **Protective barrier**
- Possibility of application in any type



## **Cuo THIN FILMS FOR PHOTOVOLTAICS**

CuO layers have been a very intensive area of research for many scientific institutions, as a potentially active layers absorbing light in solar cells, in particular as an alternative to CdTe or Si. Until now, technology has been the main barrier in the application of CuO films.





of PV cell

Anti-reflective layers are created using the ALD method. It is possible to implement the solution on a large scale due to the fact that there are industrial versions of ALD reactors allowing large substrates.

## WHAT'S NEXT?

We have developed technologies that can be used successfully in photovoltaics, as well as in other fields (eg. In sensor devices). Currently, we are looking for partners for R+D projects to continue our research and work on our inventions. We are ready to adapt our technologies to specific production requirements.

> **CONTACT PERSON:** prof. dr hab. Marek Godlewski

godlew@ifpan.edu.pl